## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

a 2004 Bavid Abraham et al.

Serial No.: 10/680,260

Group Art Unit: Not Yet Assigned

Filing Date: October 8, 2003

Examiner: Unknown

For:

METHOD AND SYSTEM FOR PATTERNING OF MAGNETIC THIN FILMS

USING GASEOUS TRANSFORMATION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT

Sir:

Under the provisions of 37 CFR §1.97 through §1.99 and pursuant to applicant's duty of disclosure under 37 CFR §1.56, applicant respectfully brings the following documents listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. Copies of the listed documents are provided herewith for the convenience of the Examiner. In compliance with the concise explanation requirement under 37 CFR §1.98(a)(3), the relevance of three of these documents is discussed on page 2 of the subject application. This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicant is aware.

It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.

Please charge any deficiencies in fees and credit any overpayment of fees to Assignee's Deposit Account No. 50-0510.

Respectfully submitted

Registration No. 34,386

Sean-M. McGinn

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